

Artificial neural network for automatic alignment of electron optical devices



Summary

Introduction to Artificial Intelligence

- What is AI and why to use it
- What is machine learning
- What is an artificial neural network

State of the art in electron microscopy

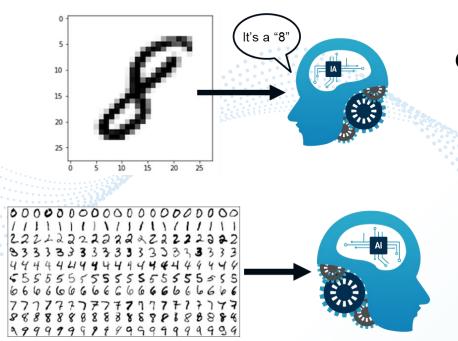
- Key role in automatic alignment
- Electron beam shaping

Al automation examples:

- Automatic tuning of optical systems within the microscope
- Real-time optimisation of experiments
- Workflow: from sample to model

Machine learning and neural networks

Artificial intelligence (AI) is **the ability of a computer to do tasks** that are usually done by humans because they require human intelligence and discernment.



Canonical example: reading hand-written digits

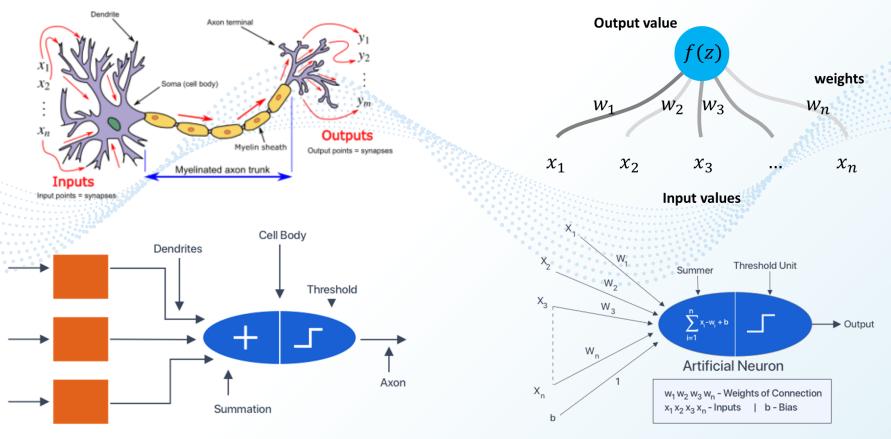
Als perform seemingly impossible tasks with speed exceeding conventional algorithms.

Machine learning is a method of data analysis that automates model building. It is based on the idea that systems can learn from data

Artificial neural networks (ANNs) are computing systems inspired animal brains.

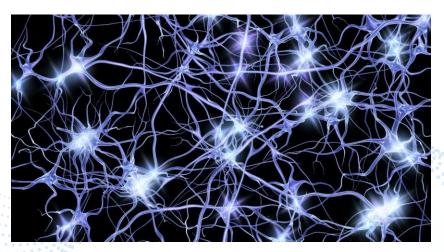
Artificial Neural Network

Artificial Neural Networks are biologically inspired network of artificial neurons configured to perform specific tasks.

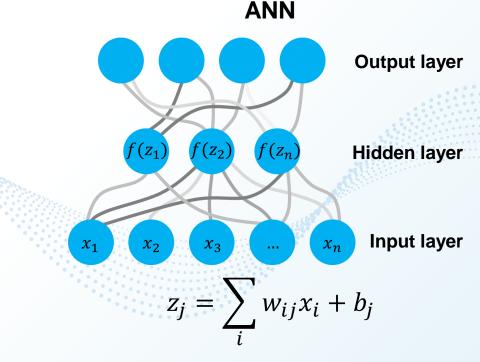


Artificial Neural Network

Brain



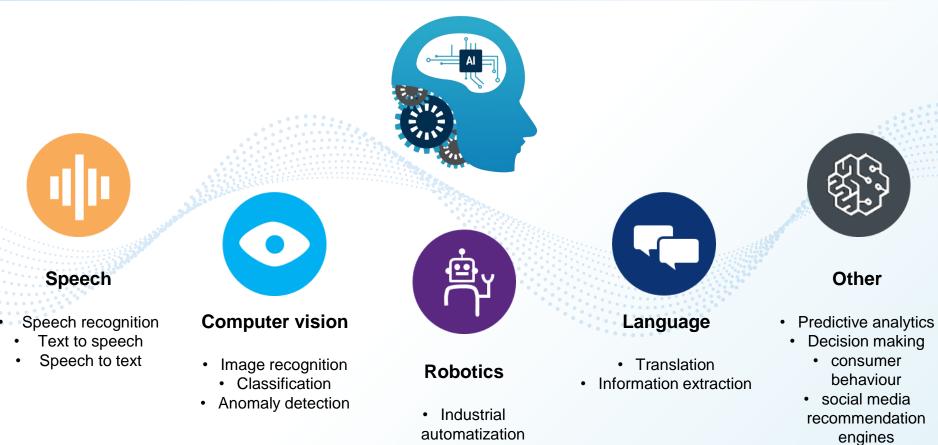
The human brain is a **network** composed of more than 100 billion neurons.



Learning is a minimisation problem

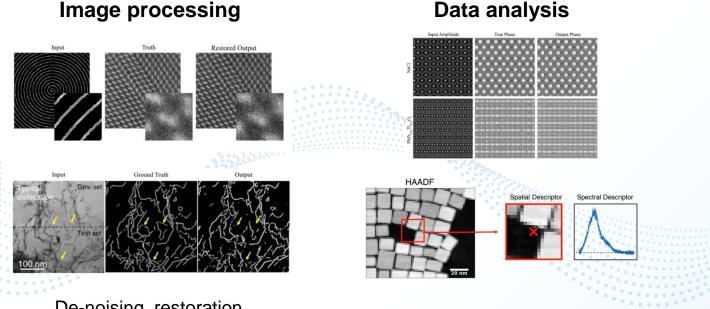
Universal approximation theorem: Any function f(x) can be approximated

General application



- automatization
- self driving vehicles

Electron microscopy applications



Automation



De-noising, restoration, segmentation, compressed sensing

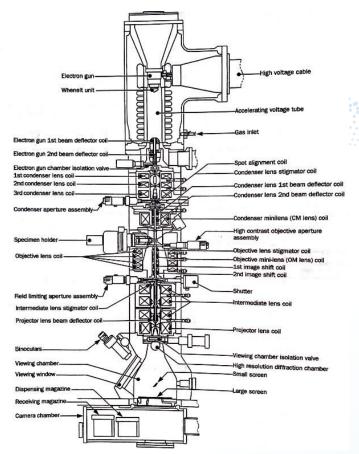
Exit wave reconstruction, holography and ptycography

Only a few timid approaches to automatic alignment.

J.M. Ede, Mach. Learn.: Sci. Technol. 2 (2021) 011004

TEM automation

Automation is not a new idea in electron microscopy



In its basic configuration, a TEM is a fairly complicated machine.

Modern microscopes are equipped with a:

- A number of cameras
- Detectors
- Energy filters
- Spectrometers
- Aberration correctors

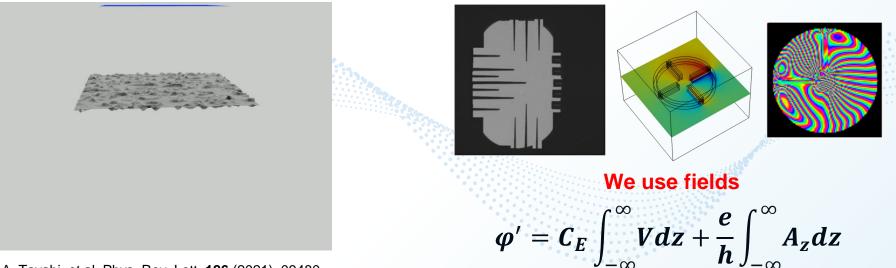
Coming very soon a variety of beam shaping devices

As research progresses this complexity is becoming the true bottleneck of further instrumental development

Beam Shaping: the next frontier

Ensemble of techniques used to control the shape of the electron wave function

We exploits MEMS technology to put electrodes directly along the electron beam path

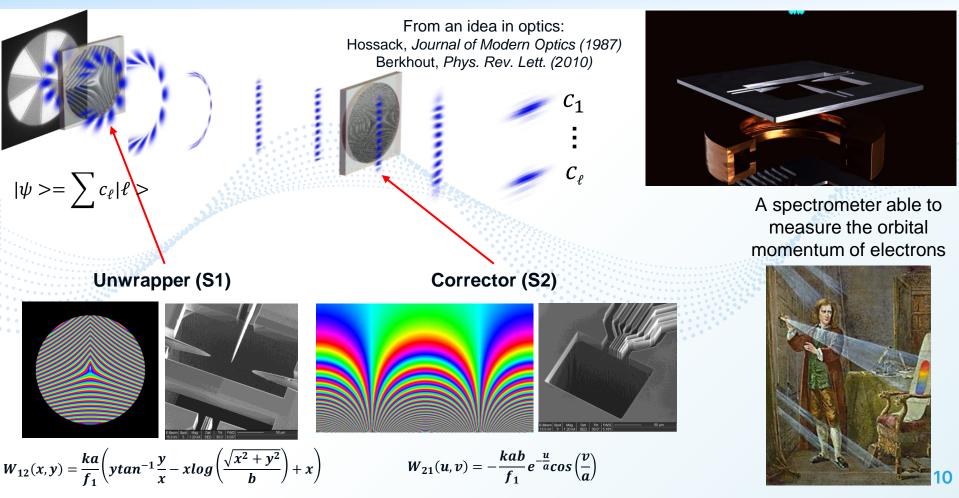


A. Tavabi et al. Phys. Rev. Lett. 126 (2021), 09480 Bechè et al. Nat. Phys. 10 (2016) 26
A.M. Blackburn Ultramic. 136 (2014) 127–143
Vanacore et al Nat. Mat. 18, (2019) 573–579
G. Pozzi et al., Ultramicroscopy 181, 191 (2017)
Verbeeck, et al., Nature 467 (2010) 301–304
A.M. Blackburn et a. Ultramicroscopy 136 (2014)
A. Tavabi, et al. Scientific reports 8 (1), 5592

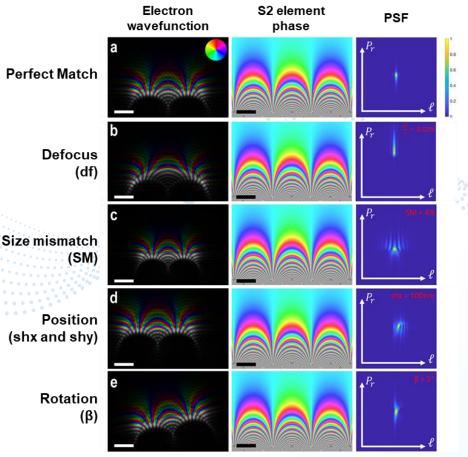
The phase shift depends on the electric and magnetic fields

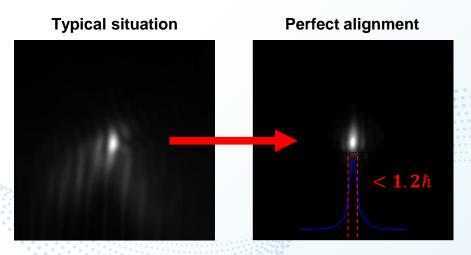
We can arbitrarily tune the phase: programmable phase plate!

The OAM sorter



Sorter alignment: crucial point





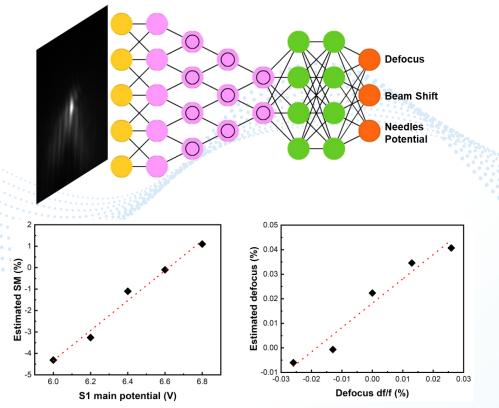
Manual alignment of the sorter is possible but takes several minutes and a certain degree of skills.

We want to move the focus from the alignment of the sorter to the actual material investigation

We need a fast and reliable alignment tool

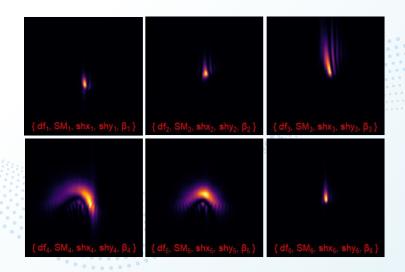
Fitting aberrations with an ANN

Convolutional neural network is a class of deep neural networks most commonly applied to analysing visual imagery



We can still improve through an iterative process.

We prepared a database of **20000** simulated spectra. Plus a second database of **2000** images for validation.

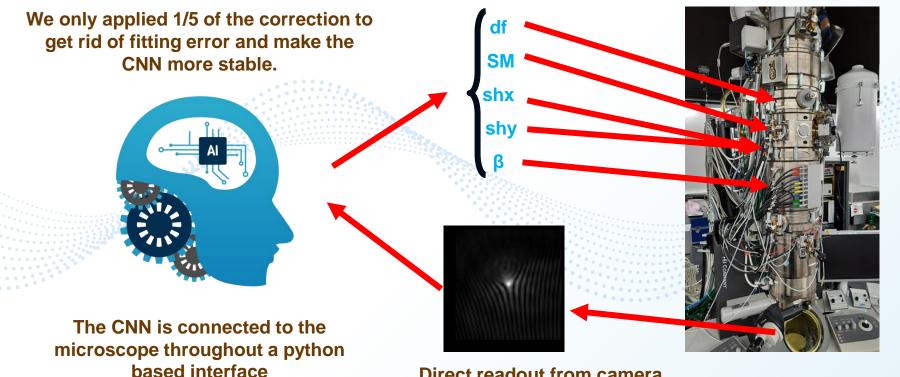


We used a free space propagation algorithm based $U_z(u,v) = \frac{e^{ikz}}{i\lambda z} \iint U_0(x,y) e^{-ik\frac{xu+yv}{z}} dxdy$

And a simple quadratic phase term for the lenses:

$$\Psi_L = e^{i\frac{\pi r^2}{f\lambda}}$$

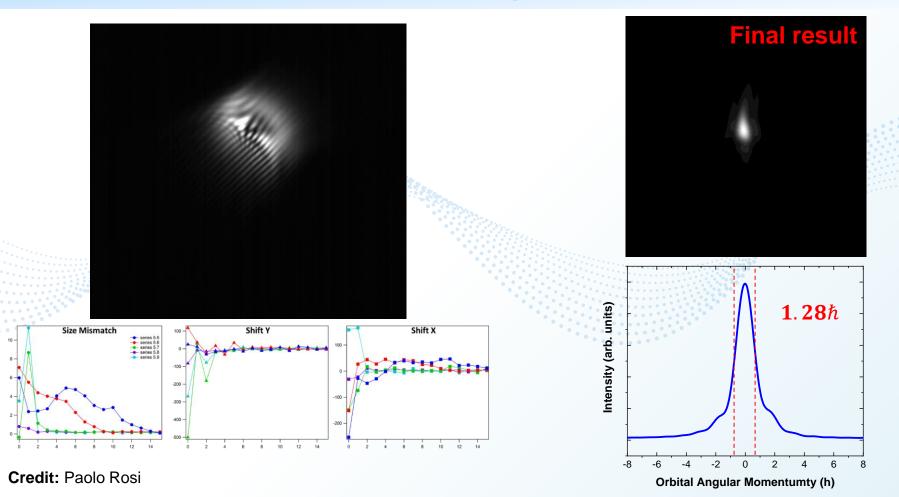
Automatic Alignment



Direct readout from camera

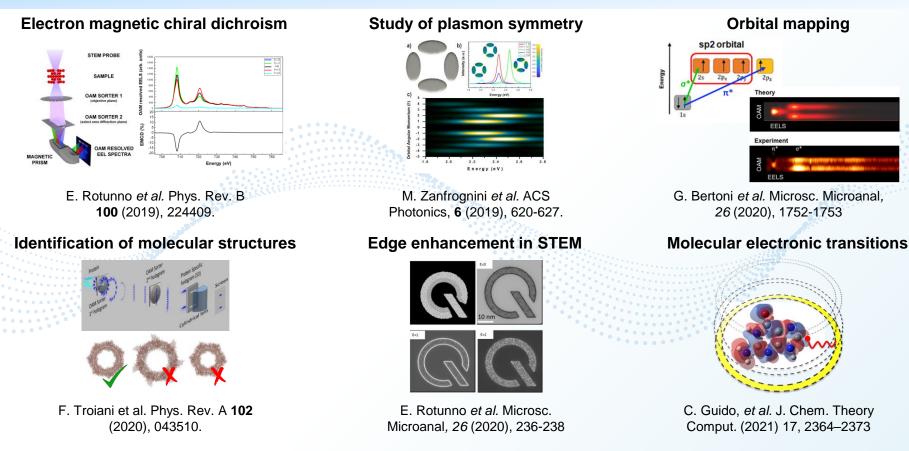
Credit: Dieter Weber 13 Alexander Clausen

Automatic Alignment



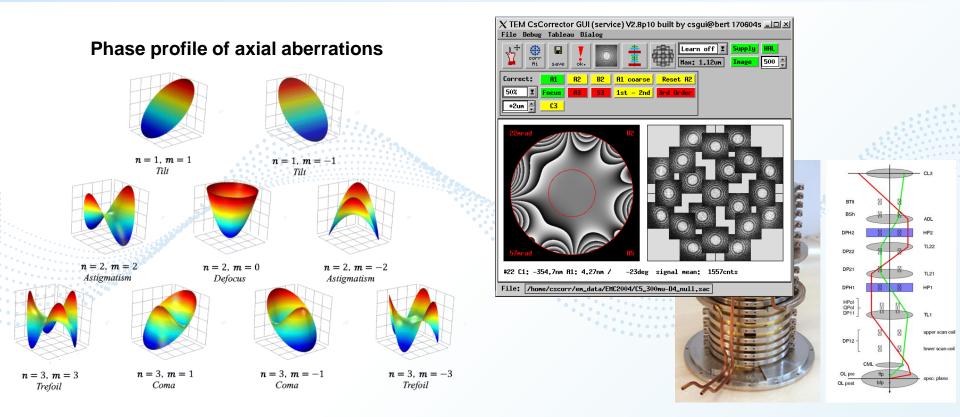
14

OAM sorter applications



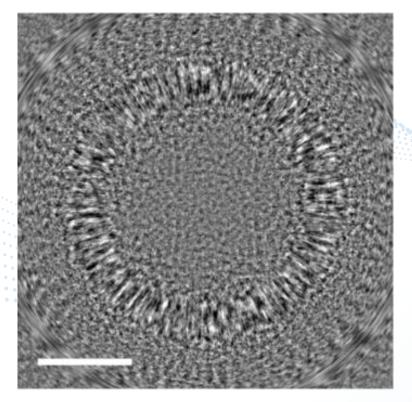
Most of the practical applications of the sorter require a resolution of 1ħ

Measuring lens aberrations



Larger numerical aperture → higher resolutions Can an ANN do better?

The Ronchigram



Ronchigram is the convergent beam diffraction pattern of an amorphous materials.

The structure of the Ronchigram encodes information about the aberration phase field across the objective aperture.

We build a database of simulated 20000 images

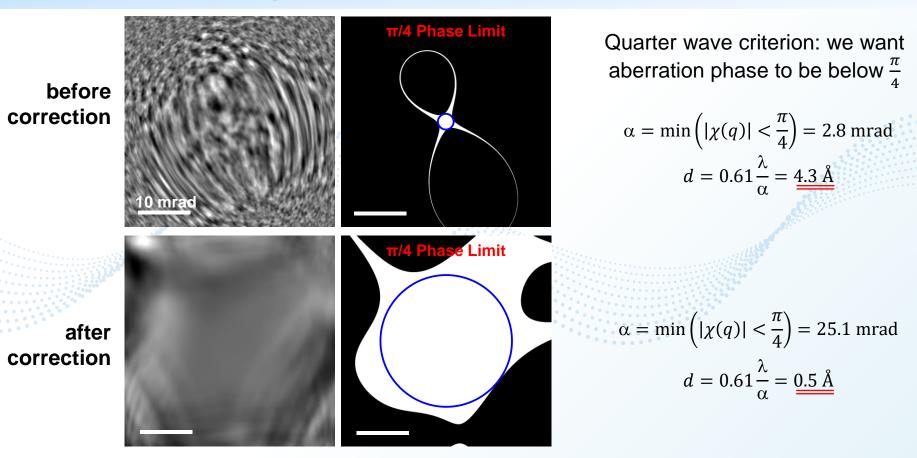
Aberrations range:

C1 (defocus) = [-2000nm, -1000nm]	MAE = 23 nm
A1 (2-fold ast.) = [-100nm, +100nm]	MAE = 5 nm
B2 (coma) = [-1um, +1um]	MAE = 49 nm
A2 (3-fold ast.) = [-1um, +1um]	MAE = 38 nm
C3 = [-100um, +100um]	MAE = 4 μm

Credit: Giovanni Bertoni

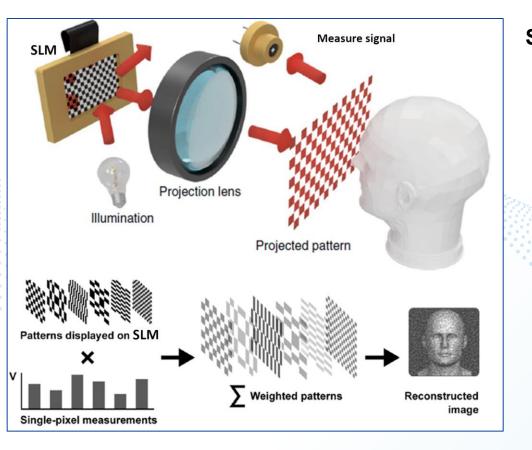
ANN fitting error:

Fitting aberrations with an ANN



Comparable with conventional means but probably faster.

Real-time optimisation of experiments



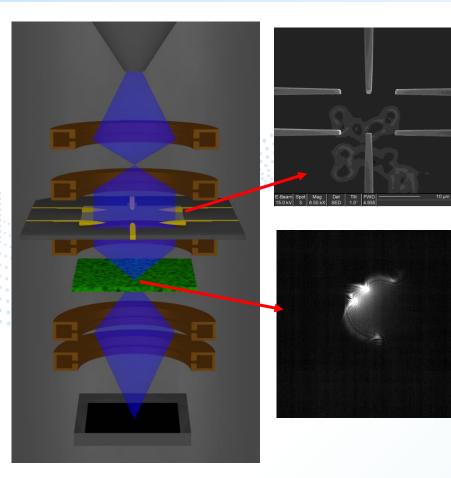
Single Pixel Imaging is a weighted sum of illumination patterns with their respective total transmitted intensity

Benefit: reconstruct the image with less measurements than the number of pixels. Easy implementation of compressed sensing algorithm.

Useful for beam sensitive materials

We need a spatial light modulator for electron beams

Electron Single Pixel Imaging



We can use our custom electron-optics as an illumination pattern generator.

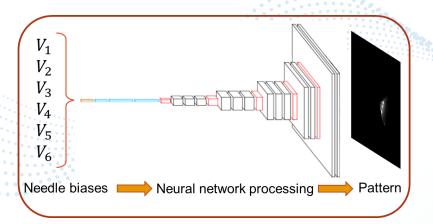
Controlling caustic pattern is a rather challenging problem.

Minor changes of the electric field will significantly affect the quality of the patterns in term of shape and position.

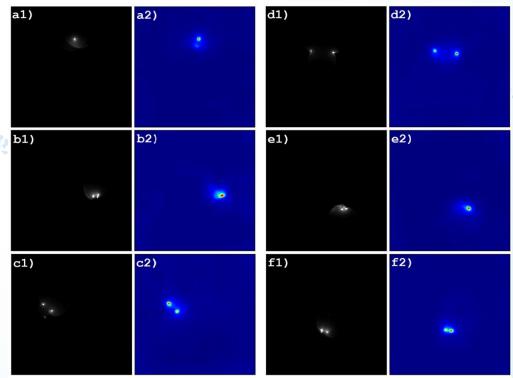
Prediction of caustic patterns with ANN

Al can offer two advantages:

- 1) Improve control over pattern generation
- 2) Optimize the measurement process



We trained a ANN to return the illumination patterns from the nominal applied biases

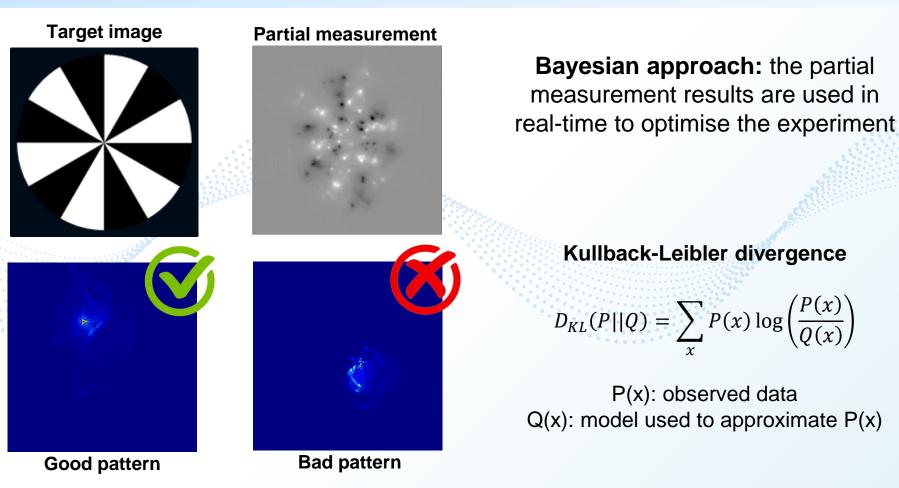


Training on experimental data!!!

Credit: Lorenzo Viani

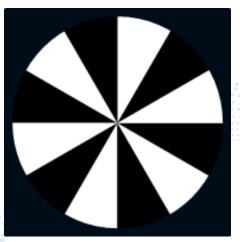
Thanks' to the speed of ANN, patterns can be computed in real time

Adaptive pattern generation



Optimal ESPI conditions

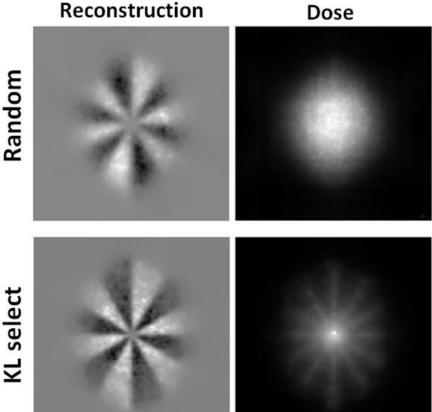
Target image



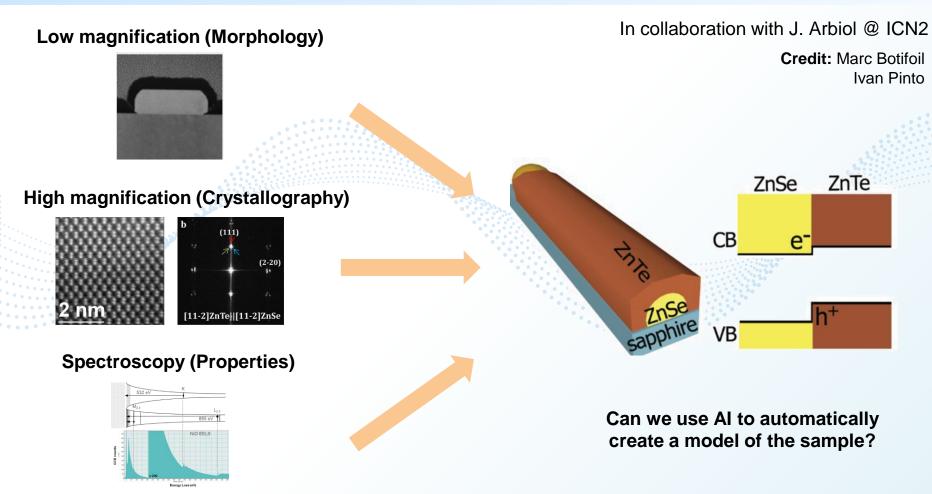
Random

Two reconstructions obtained with the same number of patterns (5000).

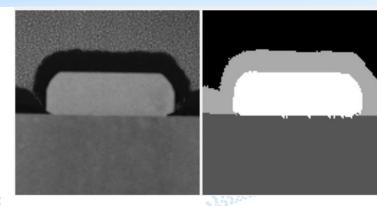
The algorithm implementing KL divergence produces sharper images by distributing the dose where it is most needed.



Workflow automation



Automatic data analysis



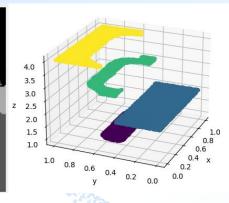
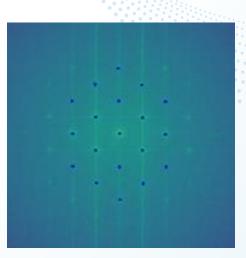


Image segmentation

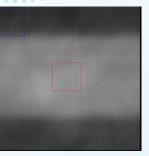
We use the segmented image to drive the acquisition of a series of atomically resolved images and chemical maps.

Automatic Indexing

Al able to accurately find diffraction spots to know the phase and orientation of every crystalline domain, or to automate the production of strain field maps.



ZB Ge [011]



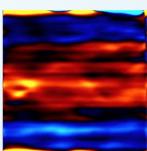
plane: [-1 0 3] to x: 147.3390872783262

30,96375653207352

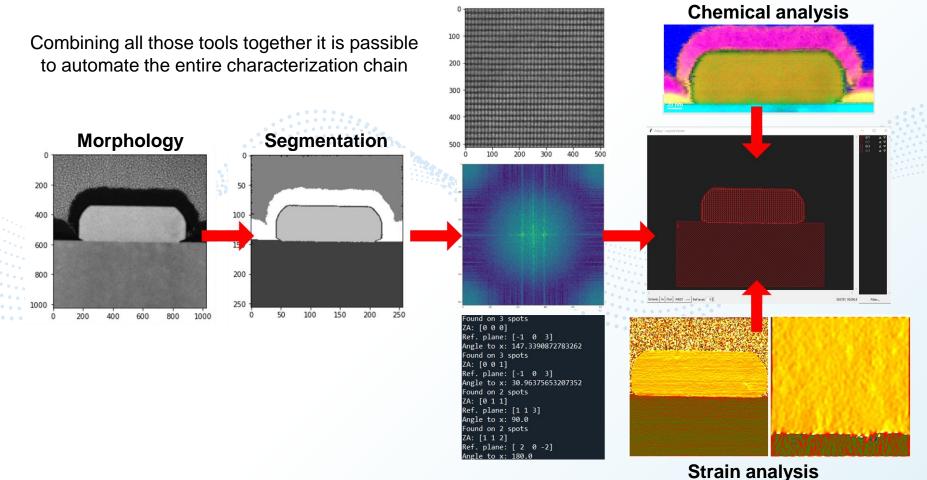
on 3 spots 0 0 1] plane: [-1 0 3]

spots

plane: [2 0 -2]



From sample to model



Conclusive remarks

AI can:

- Improve data quality
- Speed up data analysis
- Take care of the alignment
 - Custom optics
 - Conventional lenses
- Optimize in real time experiments
- Drive full workflows

AI will:

- Make TEM more accessible (in compliance with FAIR principles)
- Increase the TEM throughput
 Availability of TEM data for Al application
- Enable new experiments

Acknowledgement



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Thank you for your kind . attention! Any questions?